



IFW

THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Confirmation No. 9620

Masanobu NOGOME et al.

Attorney Docket No. 2003_1075A

Serial No. 10/630,900

Group Art Unit 2818

Filed July 31, 2003

Examiner Mai Huong Tran

SEMICONDUCTOR DEVICE AND
MANUFACTURING METHOD THEREOFINFORMATION DISCLOSURE STATEMENT

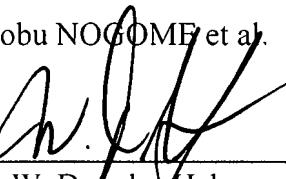
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Enclosed herewith is copy of a Japanese Office Action and the reference cited in the Japanese Office Action, JP 2000-357693 along with the English language abstract and corresponding US Patent No. 6,462,419, and US Patent No. 6,440,846. The Japanese Office Action was recently issued in a Japanese application corresponding to the above-referenced U.S. patent application. In view of the fact that the Issue Fee for the above-referenced U.S. patent application was paid on September 26, 2005, the USPTO is respectfully requested to simply place the attached materials in the file.

Respectfully submitted,

Masanobu NOGOME et al.

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THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEES FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975